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## APPLICANTS

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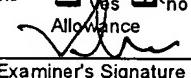
\*\* CONTINUING DATA \*\*\*\*\* NME LV

\*\* FOREIGN APPLICATIONS \*\*\*\*\* YEL LV

JAPAN 2002-310257 10/24/2002

## IF REQUIRED, FOREIGN FILING LICENSE GRANTED

\*\* 01/17/2004

Foreign Priority claimed	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY	SHEETS	TOTAL	INDEPENDENT
35 USC 119 (a-d) conditions met	<input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> Met after Allowance	JAPAN	DRAWING 9	CLAIMS 95	CLAIMS 13
Verified and Acknowledged	Examiner's Signature  Initials 				

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## TITLE

Method for cleaning plasma etching apparatus, method for plasma etching, and method for manufacturing semiconductor device

FILING FEE	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees  <input type="checkbox"/> 1.16 Fees ( Filing )  <input type="checkbox"/> 1.17 Fees ( Processing Ext. of time )  <input type="checkbox"/> 1.18 Fees ( Issue )
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